

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re patent application of

Shuzo Sato et al

Serial No. 09/800,580

Filed: March 8, 2001

Title: METHODS FOR PRODUCING AND POLISHING SEMICONDUCTOR DEVICE AND
POLISHING APPARATUS

Confirmation No. 5367

Group Art Unit: 1765

Examiner: Lan Vinh

COMMENTS ON EXAMINER'S STATEMENT OF REASONS FOR ALLOWANCE

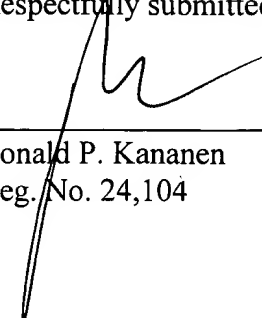
Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The allowing papers of June 4, 2004 are acknowledged with appreciation. While there were no reasons for allowance as to the allowed claims 25 to 52, and 45 to 52, it is noted that reasons were provided of record in the Action of March 16, 2004. The subject matter of allowable claim 44 was engrafted to claim 15. To the extent that the Examiner's Statement of Reasons for Allowance as to claim 44 states, implies or is construed to mean that the claim is allowable over the prior art because the Examiner believes the claims should be interpreted to include one or more features or limitations not recited therein, it should be noted that claim 44 was a dependent claim based on another combination claim. Thus, Applicant notes that there is no particular limitation in the allowed combination claims that is more critical than any other. The issuance of the historical Examiner's Statement of Reasons for Allowance should not be construed as surrender by Applicant of any subject matter, or an admission that only that feature is necessary to patentability. It is the intent of Applicant, through their attorney, to construe the

allowed claims so as to cover the invention disclosed in the present application and all equivalents to which the claimed invention is entitled.

Respectfully submitted,



Ronald P. Kananen
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Date: July 12, 2004

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